

Reply under 37 CFR 1.116 Expedited Procedure Examining Group 1756



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:) Docket No: LAM2P257 5
Ko et al.	Group Art Unit: 1756
Application No: 09/894,230) Examiner: J. Ruggles
Filed: June 27, 2001) October 27, 2003
For: APPARATUS AND METHOD FOR ARGON PLASMA INDUCED ULTRAVIOLET LIGHT CURING STEP FOR INCREASING SILICON-CONTAINING PHOTORESIST SELECTIVITY))))
<u>CERTIFICATE OF MAILING</u>	

I hereby certify that this correspondence is being deposited with the United States Postal Service as

First Class Mail to: Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 on

October 27, 2003.

Melinda M. Ward

REQUEST FOR RECONSIDERATION

Commissioner for Patents Washington, D.C. 20231

Dear Sir:

This Communication is in response to the Office Action dated August 29, 2003. Please amend the specification and consider the following arguments:

Amendments to the Specification begin on page 2 of this paper.

A current listing of the claims are provided for the Examiner's convenience which begins on page 3 of this paper.

Remarks/Arguments begin on page 6 of this paper.